

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:

Yuichi MATSUI

Appln. No.:

Filed: Herewith

For: SEMICONDUCTOR DEVICE AND MANUFACTURING METHOD THEREOF

\* \* \*

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. § 1.56, and without any  
assertion as to materiality or prior art effect, the  
documents listed on the attached Form PTO-1449 are hereby  
cited.

Documents AJ-AO and BJ-BN on the attached List are  
cited in the specification, on pages 2-3, and their  
relevance is indicated therein.

Respectfully submitted,

NHS:lmb

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1751 Pinnacle Drive, Suite 500  
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By: Nelson H. Shapiro  
Nelson H. Shapiro  
Reg. No. 17,095

April 22, 2004

<b>FORM PTO-1449</b>				<b>Atty. Docket No.</b> XA-10070		<b>Appln. No.</b>	
<b><u>LIST OF DOCUMENTS CITED BY APPLICANT</u></b>							
				<b>Applicant</b> Yuichi MATSUI			
				<b>Filing Date</b> HEREWITH		<b>Group</b>	
<b>U.S. PATENT DOCUMENTS</b>							
<b>Examiner Initial</b>		<b>Document Number</b>	<b>Date</b>	<b>Name</b>	<b>Class</b>	<b>Sub-class</b>	<b>Filing Date</b>
	AA	5,622,888	4/22/97	Sekine et al.	438	398	
	AB	6,235,572	5/22/01	Kunitomo et al.	438	240	
	AC	6,243,255	6/5/01	Kuge et al.	361	528	
	AD	2003/0011022	1/16/03	Manabe	257	314	
	AE	6,576,928	6/10/03	Hiratani et al.	257	68	
	AF	6,673,461	1/6/04	Chazono et al.	428	469	
	AG	5,970,337	10/19/99	Nishioka	438	240	
	AH	2003-0151083	8/14/03	Matsui et al.	257	310	
	AI						
<b>FOREIGN PATENT DOCUMENTS</b>							
<b>Examiner Initial</b>		<b>Document Number</b>	<b>Date</b>	<b>Country</b>	<b>Class</b>	<b>Sub-class</b>	<b>Translation</b>
	AJ	8-139288	5/31/96	JAPAN			abstract
	AK	2000-12796	1/14/00	JAPAN			abstract
	AL	2000-82639	3/21/00	JAPAN			abstract
	AM	2002-164516	6/7/02	JAPAN			abstract
	AN	2003-243534	8/29/03	JAPAN			abstract
	AO	2001-77108	3/23/01	JAPAN			abstract
<b>OTHER</b> (including author, title, date, pertinent pages, etc.)							
	AP	Rosenfeld, D. et al., "Structural and morphological characterization of Nb <sub>2</sub> O <sub>5</sub> thin films deposited by reactive sputtering", <u>American Vacuum Society</u> , 1994, pp. 135-139.					
	AQ						
	AR						
<b>Examiner</b>				<b>Date Considered</b>			
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.							

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XA-10070

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Applicant

Yuichi MATSUI

Filing Date

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**U.S. PATENT DOCUMENTS**

Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
	BA						
	BB						
	BC						
	BD						
	BE						
	BF						
	BG						
	BH						
	BI						

**FOREIGN PATENT DOCUMENTS**

Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
	BJ	5-345663	12/27/93	JAPAN			abstract
	BK	10-12043	1/16/98	JAPAN			abstract
	BL	2001-284158	10/12/01	JAPAN			abstract
	BM	8-31951	2/2/96	JAPAN			abstract
	BN	11-330415	11/30/99	JAPAN			abstract
	BO						

**OTHER** (including author, title, date, pertinent pages, etc.)

	BP	
	BQ	
	BR	

Examiner

Date Considered

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.